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[54] **METHOD AND APPARATUS FOR APPLYING A COATING MATERIAL TO A SUBSTRATE**

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[58] **Field of Search** ..... **427/240, 348; 118/52, 118/320**

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#### [57] **ABSTRACT**

A coating apparatus comprises a spinning chuck rotatably supported within an enclosure and securely holding a substrate thereon. A coating material is applied onto the surface of the substrate and distributed over the substrate by centrifugal forces. An annular air duct is disposed in surrounding and spaced relation to the spinning chuck, and a disk is placed between the air duct and the spinning chuck and has a plurality of guide vanes. Fans are provided in the air duct to develop a positive flow of air over the substrate. The flow of air is guided by the guide vanes in a direction identical to the direction of rotation of the substrate so as to eliminate undesirable deposition from the end edges of the substrate.

**4 Claims, 3 Drawing Sheets**

